

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Kenichi SHIRAIISHI

Serial No. 10/589,437

Group Art Unit: 2851

Confirmation No. 9870

Filed: August 1, 2007

Examiner: Mesfin T. Asfaw

For: EXPOSURE APPARATUS, SUPPLY METHOD AND RECOVERY METHOD,
EXPOSURE METHOD, AND DEVICE PRODUCING METHOD

RESPONSE

Mail Stop Amendment

Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Sir:

This is in response to the Office Action mailed November 24, 2009, which has a period for response set to expire on February 24, 2010. A Petition for a three-month extension of time, together with the requisite fee for same, is submitted herewith, thereby extending the period for response to May 24, 2010.

Reconsideration of the claims is respectfully requested. The following remarks are respectfully submitted.

A list of the claims begins at page 2; and

Remarks begin at page 9.